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35C.14179

PATENT APPLICATION



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

YOUICHI ANDO, ET AL.

Application No.: 09/722,454

Filed: November 28, 2000

For: METHOD FOR MANUFACTURING )  
ELECTRON BEAM DEVICE, )  
METHOD FOR MANUFACTURING )  
IMAGE FORMING APPARATUS, )  
ELECTRON BEAM DEVICE AND )  
IMAGE FORMING APPARATUS )  
MANUFACTURED THOSE )  
MANUFACTURING METHODS, )  
METHOD AND APPARATUS FOR )  
MANUFACTURING ELECTRON )  
SOURCE AND APPARATUS FOR )  
MANUFACTURING IMAGE )  
FORMING APPARATUS )

Examiner: Not Yet Assigned

Group Art Unit: 2879

May 17, 2001

Assistant Commissioner for Patents  
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under  
37 C.F.R. § 1.56 and in accordance with the practice under  
37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is  
directed to the document listed on the enclosed Form  
PTO-1449. A copy of the listed document is also enclosed.

The concise explanation of relevance for the  
non-English document is found on the specification where it

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TC 2800 MAIL ROOM


is cited and as follows. A spark discharge is said to be affected by a surface condition in a highly evacuated space. To increase spark discharge therefore, the spark discharge is affected on a highly evacuated space.

CONCLUSION

It is respectfully requested that the above information be considered by the Examiner and that a copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Applicants' undersigned attorney may be reached in our New York office by telephone at (212) 218-2100. All correspondence should continue to be directed to our address given below.

Respectfully submitted,



Attorney for Applicants

Registration No.



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